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Micro- and Nano-Sensor for Iot Security

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VARIATIONS IN SEMICONDUCTOR MANUFACTURING



- Random variations in semiconductor manufacturing process
 - Sources: gate oxide thickness, random dopant fluctuations, device geometry
 - Consequences: variations in performance (speed, sensitivity, etc.)
- Should be minimized, cannot be eliminated
- Can we take advantage of it?

PHYSICALLY UNCLONABLE FUNCTIONS (PUF)



Process variation

SRAM DRAM RF transmitter Arbiter chain Ring oscillator

Unique fingerprint

Reset state Retention capability Propagation delay Phase/magnitude error Cell charge leakage

PUF key

Unique random number 0101101101000...

PUF APPLICATION: TWO-FACTOR AUTHENTICATION

4



= PUF device

CMOS IMAGE SENSOR-BASED PUF



CMOS IMAGE SENSOR-BASED PUF

Unique fixed pattern noise (FPN) appears in the captured images



Same model, different noise patterns

PROTOTYPING AND EVALUATION



Sony IMX377 (12 megapixels)

Google Nexus 5X

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- Camera2 API
- Raw and jpeg images
- Temperature-controlled chamber
- Maximum ISO
- Minimum shutter speed
- Additional experimental results on Google Nexus 5 available in the paper

EXPERIMENTAL RESULTS: KEY EXTRACTION

